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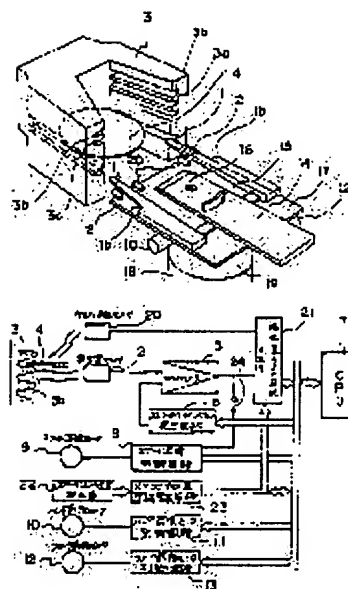
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(54) WAFER TRANSFER DEVICE

(57)Abstract:

PURPOSE: To stably take in and out a wafer with no useless motion, by detecting the positional level of a wafer storing groove and the presence of the wafer in this groove, at the front end face of a cassette.

CONSTITUTION: A stage 17 moves the front face of a wafer cassette 3 vertically, and sensors 2, 20 detect a groove 3b and a wafer 4. A groove detection signal from the sensor 2 is compared with a signal from a threshold generating circuit 6 by a comparator 5, and is stored as a groove detection data into a data line in a memory 21, and a wafer detection signal from the sensor 20 is stored as a wafer detection data in the data line in the memory 21. A signal from a stage vertical position detector 22 is converted into a memory address for the memory 21, by means of an address generating circuit 23, and therefore, the detection data of the groove and the wafer are stored in the memory 21. Thus, the precise position of a wafer in the cassette may be selected.



LEGAL STATUS

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